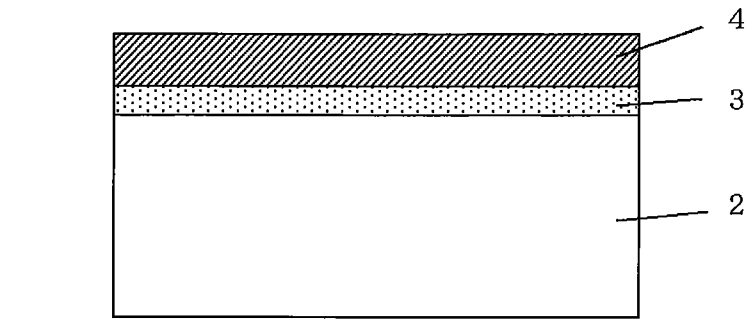
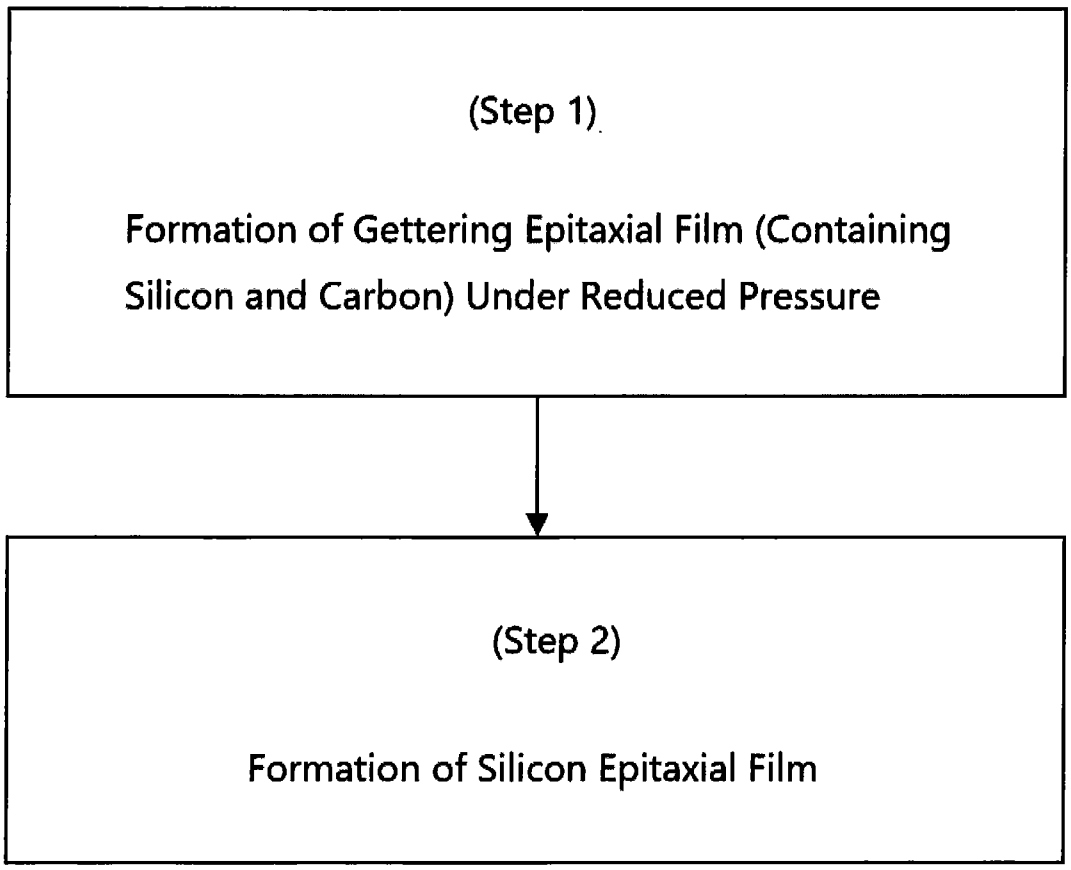
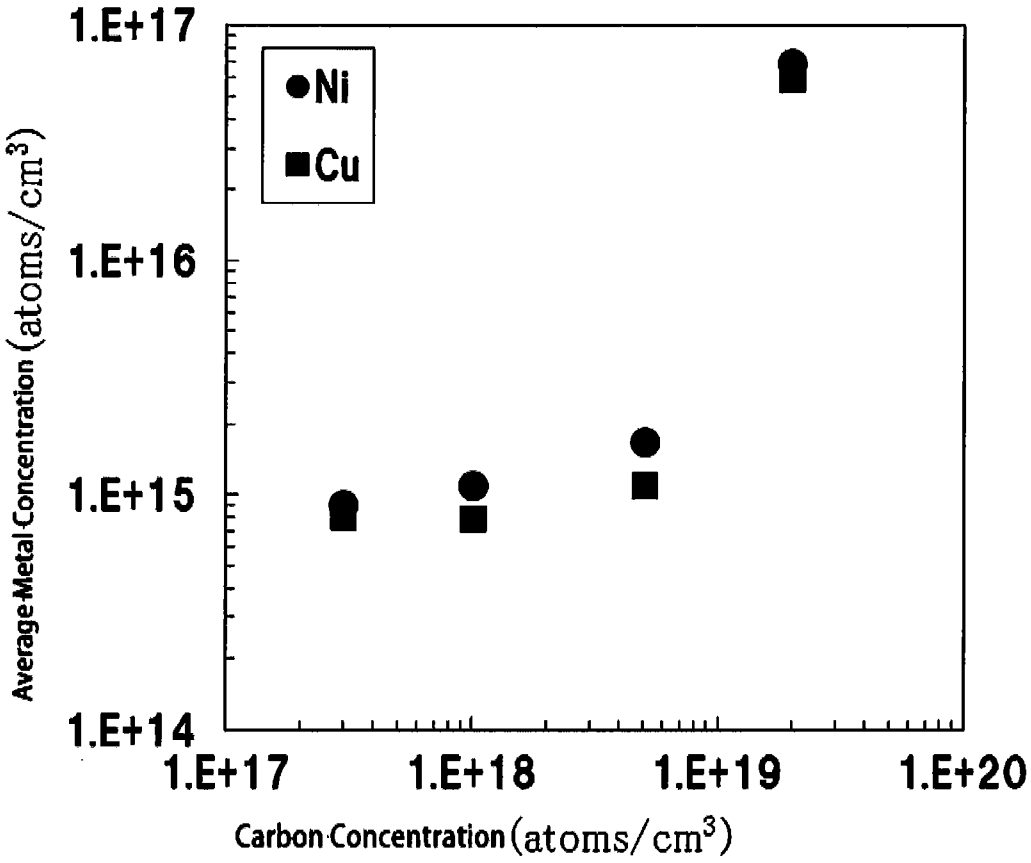
[FIG. 1]


1
4
3
2

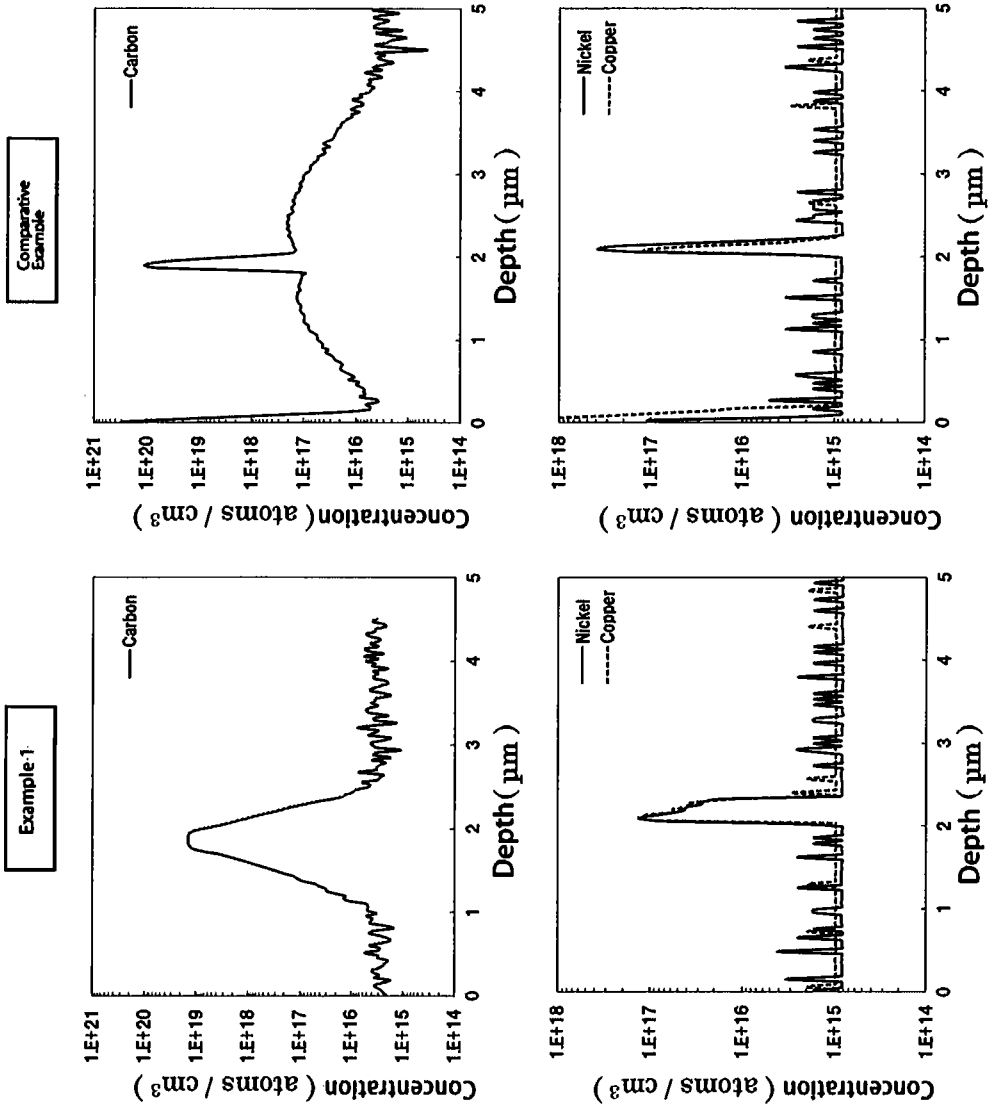
[FIG. 2]


(Step 1)
Formation of Gettering Epitaxial Film (Containing Silicon and Carbon) Under Reduced Pressure
(Step 2)
Formation of Silicon Epitaxial Film

[FIG. 3]

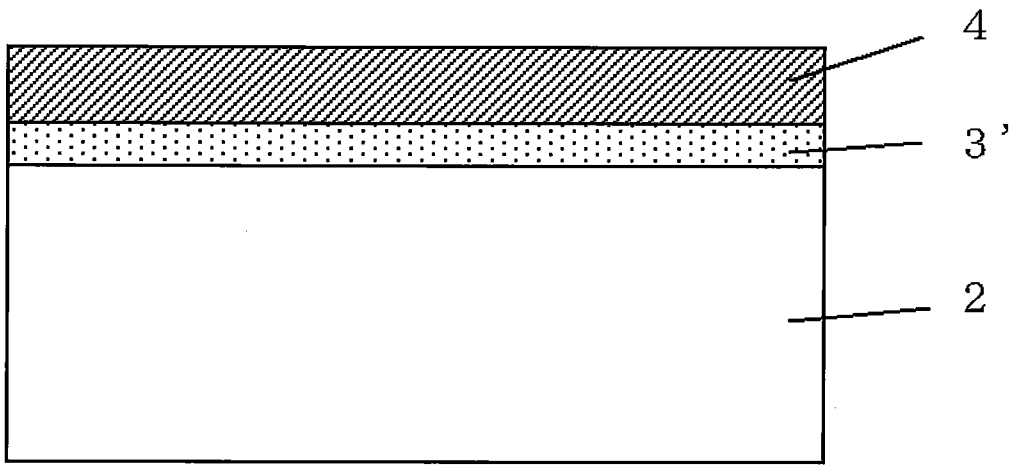

1.E+17
1.E+16
1.E+15
1.E+14
●Ni
■Cu
Average Metal Concentration (atoms/cm3)
1.E+17
1.E+18
1.E+19
1.E+20
Carbon Concentration (atoms/cm3)

[FIG. 4]

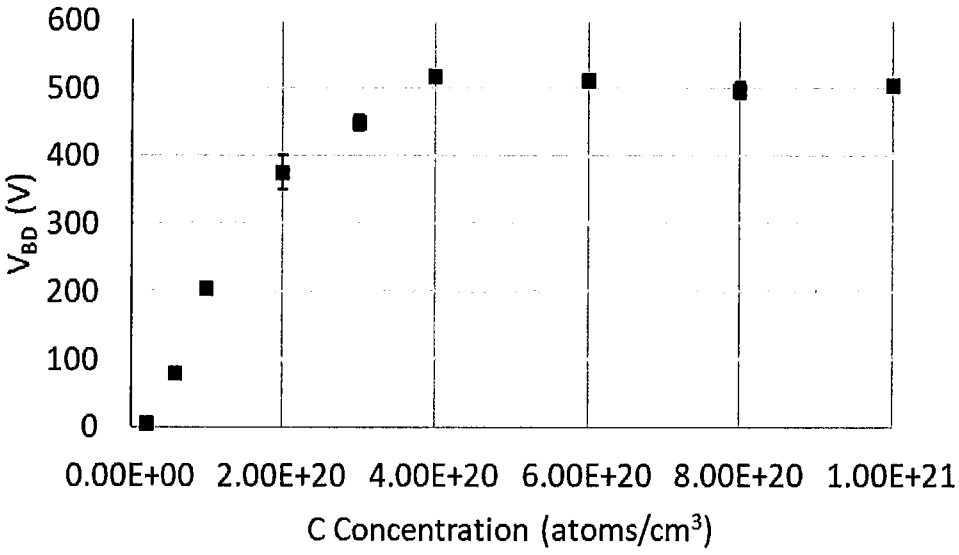

Example 1
Comparative Example
Carbon
Nickel
Copper
Concentration (atoms / cm3)
Depth (μm)

[FIG. 5]

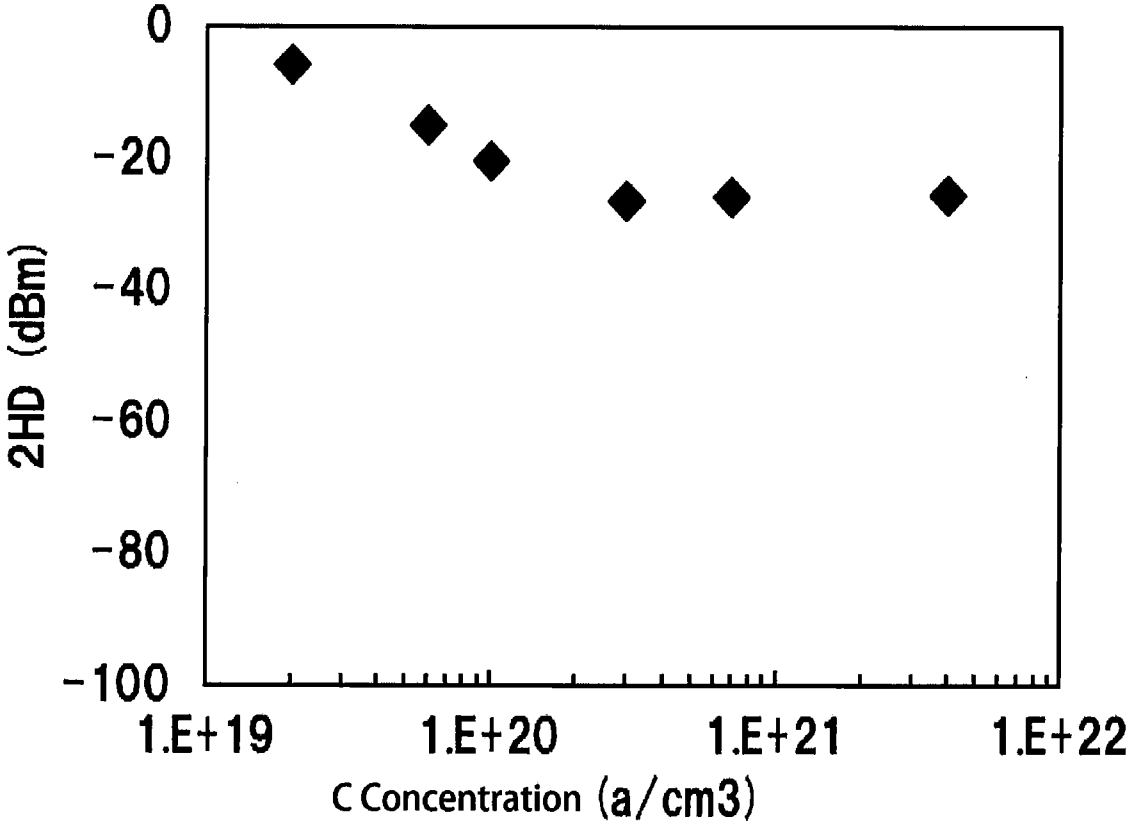
1'


4
3'
2

[FIG. 6]


600
500
400
300
200
100
0
V_{BD} (V)
0.00E+00
2.00E+20
4.00E+20
6.00E+20
8.00E+20
1.00E+21
C Concentration (atoms/cm^3)

[FIG. 7]


0
-20
-40
-60
-80
-100
2HD (dBm)
1.E+19
1.E+20
1.E+21
1.E+22
C Concentration (a/cm3)